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First Named Inventor:	Weidong Yang
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT
(Use several sheets if necessary)

U.S. Patent Documents

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
8.	5,214,492	25-May-93	LoBianco et al.	356	400	8/2/1991
2.	5,216,257	Jun. 1, 1993	Brueck et al.	250	548	7/9/1990
8.	5,307,152	Apr. 26, 1994	Boehlein et al.	356	376	9/29/1992
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8.	5,805,290	Sep. 8, 1998	Ausschnitt et al.	356	401	5/2/1996
8.	5,969,819	Oct. 19, 1999	Wang	356	371	6/5/1997
8.	6,077,756	Jun. 20, 2000	Lin et al.	438	401	4/24/1998
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16.	US 2003/0042579	Mar. 6, 2003	Schulz	257	629	8/30/2001
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21.	WO 02/065545 A2	Aug. 22, 2002	PCT	H01L	21/66	2/12/2001	
22.	WO 02/069390 A2	Sep. 6, 2002	PCT	H01L	21/66	2/27/2001	

Examiner

Date Considered

*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



		WO 02/084213 A1	Oct. 24, 2002	PCT	G01B	Nov-00	4/10/2001	
	24.	WO 02/25723 A2	Mar. 28, 2002	PCT	H01L	21/66	9/19/2000	
	25.	WO 04/008068 A1	Jan. 22, 2004	PCT	G01B	11/27	10/26/01	
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	26.	Bischoff, J. et al., "Light Diffraction Based Overlay Measurement" <i>Proceedings of SPIE</i> , Vol. 4344 (2001) Pages 222-233						
	27.	Michaelis, A. et al., "Spectroscopic Anistropy Micro-Ellipsometry (SAME) for determination of lateral and vertical dimensions of sub-micron lithographic structures" <i>IEEE Catalog Number 99TH8453</i> (1999) Pages 131-134						
	28.	NanoWave:Technology/development tools, http://www.nanowave.com/technology_applications/tech_devtoolsPR.html , 2 pages, downloaded April 9, 2002.						
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Examiner /Dennis Rosario/ Date Considered 10/09/2008

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